

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Divisional Application of:) Group Art Unit: 1765
Naoaki YAMAGUCHI et al.) Examiner: Anita Karen Alanko
Based on Serial No. 10/035,441)
Filed: January 4, 2002)
For: OPTICAL PROCESSING)
APPARATUS AND OPTICAL)
PROCESSING METHOD)

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, Applicant submits herewith a Form PTO-1449 listing references known to Applicant and requests that these references be made of record in the above identified application.

Copies of U.S. patents and U.S. publications are not enclosed in accordance with the Notice published in the Official Gazette on August 5, 2003 entitled *Information Disclosure Statements May Be Filed Without Copies of U.S. Patents and Published Applications in Patent Applications filed after June 30, 2003*, which waives the requirement under 37 CFR 1.98(a)(2)(i) for submitting a copy of each cited U.S. patent and each U.S. publication.

The references listed on the attached Form PTO 1449 were cited in parent application Serial No. 10/035,441 and predecessor Application Serial Nos. 09/547,716 and 08/451,648 and copies of the references can be found in those applications.

Respectfully submitted,



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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				Complete if Known			
				Application Number		Based on SN 10/035,441	
				Filing Date		Filed: January 4, 2002	
				First Named Inventor		Naoaki YAMAGUCHI et al.	
				Group Art Unit		1765	
				Examiner Name		Anita Karen Alanko	
Sheet	1	of	3	Attorney Docket Number		0756-7191	

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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		Office ³	Number ⁴	Kind Code ⁵ (if known)				
		JP	05-243576			09/21/1993		Abst.
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		JP	06-204132			07/22/1994		Abst.

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
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		G. Liu, S.J. Fonash, "Polycrystalline Silicon Thin Film Transistors on Corning 7059 Glass Substrates Using Short Time, Low Temperature Processing," Appl. Phys. Lett 62 (20), May 17, 1993, 1993 American Institute of Physics, pp. 2554-2556.	
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